Attorney Docket Number	7276-78462-01
Application Number	10/777,282
Filing Date	February 10, 2004
First Named Inventor	Adams
Art Unit	1797
Examiner Name	Keri A. Moss

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

U.S. PATENT DOCUMENTS

Copies of U.S. Patent documents do not need to be provided, unless requested by the Patent and Trademark Office. For patents, provide the patent number and the issue date. For published U.S. applications, provide the publication number and the publication date. For unpublished pending patent applications, provide the application number and the filing date.

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/K.M./		3,266,291	August 16, 1966	KING
/K.M./		3,478,573	November 18, 1969	KING
/K.M./		3,715,911	February 13, 1973	CHUAN
/K.M./		4,312,288	January 26, 1982	FINSTERWALDER ET AL.
/K.M./		4,549,427	October 29, 1985	KOLESAR, JR.
/K.M./		4,637,987	January 20, 1987	MINTEN *ET AL.*
/K.M./		4,674,319	June 23, 1987	MULLER *ET AL.*
/K.M./		4,935,634	June 19, 1990	HANSMA *ET AL.*
/K.M./		4,992,244	February 12, 1991	GRATE
/K.M./		5,266,801	November 30, 1993	ELINGS *ET AL.*
/K.M./		5,345,213	September 6, 1994	SEMANCIK *ET AL.*
/K.M./		5,356,756	October 18, 1994	CAVICCHI *ET AL.*
/K.M./		5,411,709	May 2, 1995	FURUKI *ET AL.*
/K.M./		5,412,980	May 9, 1995	ELINGS *ET AL.*
/K.M./		5,445,008	August 29, 1995	WACHTER *ET AL.*
/K.M./		5,469,369	November 21, 1995	ROSE-PEHRSSON *ET AL.*

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/K.M./		5,519,212	May 21, 1996	ELINGS *ET AL.*
/K.M./		5,719,324	February 17, 1998	THUNDAT *ET AL.*
/K.M./		5,742,377	April 21, 1998	MINNE *ET AL.*
/K.M./		5,750,989	May 12, 1998	LINDSAY *ET AL.*
/K.M./		5,753,814	May 19, 1998	HAN *ET AL.*
/K.M./		5,756,631	May 26, 1998	GRATE
/K.M./		5,807,758	September 15, 1998	LEE *ET AL.*
/K.M./		5,874,668	February 23, 1999	XU *ET AL.*
/K.M./		5,883,705	March 16, 1999	*MINNE ET AL.*
/K.M./		5,918,263	June 29, 1999	THUNDAT
/K.M./		5,965,452	October 12, 1999	KOVACS
/K.M./		6,005,400	December 21, 1999	THUNDAT *ET AL.*
/K.M./		6,015,869	January 18, 2000	GRATE *ET AL.*
/K.M./		6,016,686	January 25, 2000	THUNDAT
/K.M./		6,029,500	February 29, 2000	TOM
/K.M./		6,032,518	March 7, 2000	PRATER *ET AL.*
/K.M./		6,041,642	March 28, 2000	DUNCAN
/K.M./		6,050,722	April 18, 2000	THUNDAT *ET AL.*
/K.M./		6,075,585	June 13, 2000	MINNE *ET AL.*
/K.M./		6,096,559	August 1, 2000	THUNDAT *ET AL.*

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/K.M./		6,118,124	September 12, 2000	THUNDAT *ET AL.*
/K.M./		6,156,578	December 5, 2000	TOM
/K.M./		6,167,748	January 2, 2001	BRITTON JR. *ET AL.*
/K.M./		6,182,499	February 6, 2001	MCFARLAND *ET AL.*
/K.M./		6,185,992	February 13, 2001	DANIELS *ET AL.*
/K.M./		6,189,374	February 20, 2001	ADDERTON *ET AL.*
/K.M./		6,212,939	April 10, 2001	THUNDAT
/K.M./		6,253,162	June 26, 2001	JARMAN *ET AL.*
/K.M./		6,263,736	July 24, 2001	THUNDAT *ET AL.*
/K.M./		6,269,685	August 7, 2001	ODEN
/K.M./		6,280,939	August 28, 2001	ALLEN
/K.M./		6,289,717	September 18, 2001	THUNDAT *ET AL.*
/K.M./		6,295,861	October 2, 2001	TOM *ET AL.*
/K.M./		6,311,549	November 6, 2001	THUNDAT *ET AL.*
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/K.M./		6,336,353	January 8, 2002	MATSIEV *ET AL.*
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/K.M./		6,393,895	May 28, 2002	MATSIEV *ET AL.*
/K.M./		6,401,519	June 11, 2002	MCFARLAND *ET AL.*

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/K.M./		6,408,250	June 18, 2002	GRATE *ET AL.*
/K.M./		6,411,075	June 25, 2002	BATTISTON *ET AL.*
/K.M./		6,436,346	August 20, 2002	DOKTYCZ *ET AL.*
/K.M./		6,437,328	August 20, 2002	KNAUSS *ET AL.*
/K.M./		6,455,319	September 24, 2002	LEWIS *ET AL.*
/K.M./		6,457,360	October 1, 2002	DARAKTCHIEV *ET AL.*
/K.M./		6,469,293	October 22, 2002	SHIMIZU *ET AL.*
/K.M./		6,477,479	November 5, 2002	MANSKY *ET AL.*
/K.M./		6,487,523	November 26, 2002	JARMAN *ET AL.*
/K.M./		6,494,079	December 17, 2002	MATSIEV *ET AL.*
/K.M./		6,523,392	February 25, 2003	PORTER *ET AL.*
/K.M./		6,530,266	March 11, 2003	ADDERTON *ET AL.*
/K.M./		6,535,822	March 18, 2003	MANSKY *ET AL.*
/K.M./		6,535,824	March 18, 2003	MANSKY *ET AL.*
/K.M./		6,545,495	April 8, 2003	WARMACK *ET AL.*
/K.M./		6,575,020	June 10, 2003	DE CHARMOY GREY *ET AL.*
/K.M./		6,598,459	July 29, 2003	FU
/K.M./		6,606,567	August 12, 2003	GRATE *ET AL.*
/K.M./		6,650,102	November 18, 2003	HAJDUK *ET AL.*
/K.M./		6,668,627	December 30, 2003	LANGE *ET AL.*

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/K.M./		6,672,144	January 6, 2004	ADDERTON *ET AL.*
/K.M./		6,763,705	July 20, 2004	THUNDAT *ET AL.*
/K.M./		6,810,720	November 2, 2004	ADDERTON *ET AL.*
/K.M./		6,811,133	November 2, 2004	MILES
/K.M./		6,815,866	November 9, 2004	LEE
/K.M./		6,823,717	November 30, 2004	PORTER *ET AL.*
/K.M./		6,854,317	February 15, 2005	PORTER *ET AL.*
/K.M./		6,866,819	March 15, 2005	CHANDRA *ET AL.*
/K.M./		6,904,786	June 14, 2005	MATSIEV *ET AL.*
/K.M./		6,928,877	August 16, 2005	CARLSON *ET AL.*
/K.M./		6,935,165	August 30, 2005	BASHIR *ET AL.*
/K.M./		6,953,977	October 11, 2005	MLCAK *ET AL.*
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/K.M./		2003/0041653 A1	March 6, 2003	MATSIEV *ET AL.*
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